

Growth and electronic properties of TiO₂–based thin films



Mitglied der Helmholtz-Gemeinschaft

- History of development
- Motivation
- Overview of activities
- Basics of transparent conductive oxides
- Challenges and objectives
- Experimental approach
- Basics of magnetron sputtering
- Direct growth of TiO₂-based TCOs
- Two-step formation process
- Summary and Outlook
- Acknowledgements

History of development

- **CdO:** bulk 1902 (Streintz), thin film 1907 (Badeker)
 - CdO-based compounds:
 - best electrical properties
 - optical transmittance is not optimal, toxic material
- **SnO₂:** first patent 1938 (Littleton), films on glass 1942 (McMaster)
 - SnO₂:F is dominating on the market (Asahi Glass)
 - established technology, integration in large area glass production
 - fluorine-containing precursors, high environmental footprint
- **In₂O₃:** first patent 1947 (Zunick)
 - In₂O₃:Sn (ITO)
 - standard technology (sputtering), the best material available
 - expensive, metallic indium supply problems
- **ZnO:Al:** first publication 1971 (Wasa)
 - early stages of commercialization, cost-efficient production
 - environmental stability problems
- **TiO₂:Nb:** first publication 2005 (Furubayashi)

Review: Ingram et al, *J. Electroceram.* 13, 167 (2004)
Furubayashi et al, *Appl. Phys. Lett.* 86, 252101 (2005)

History of development

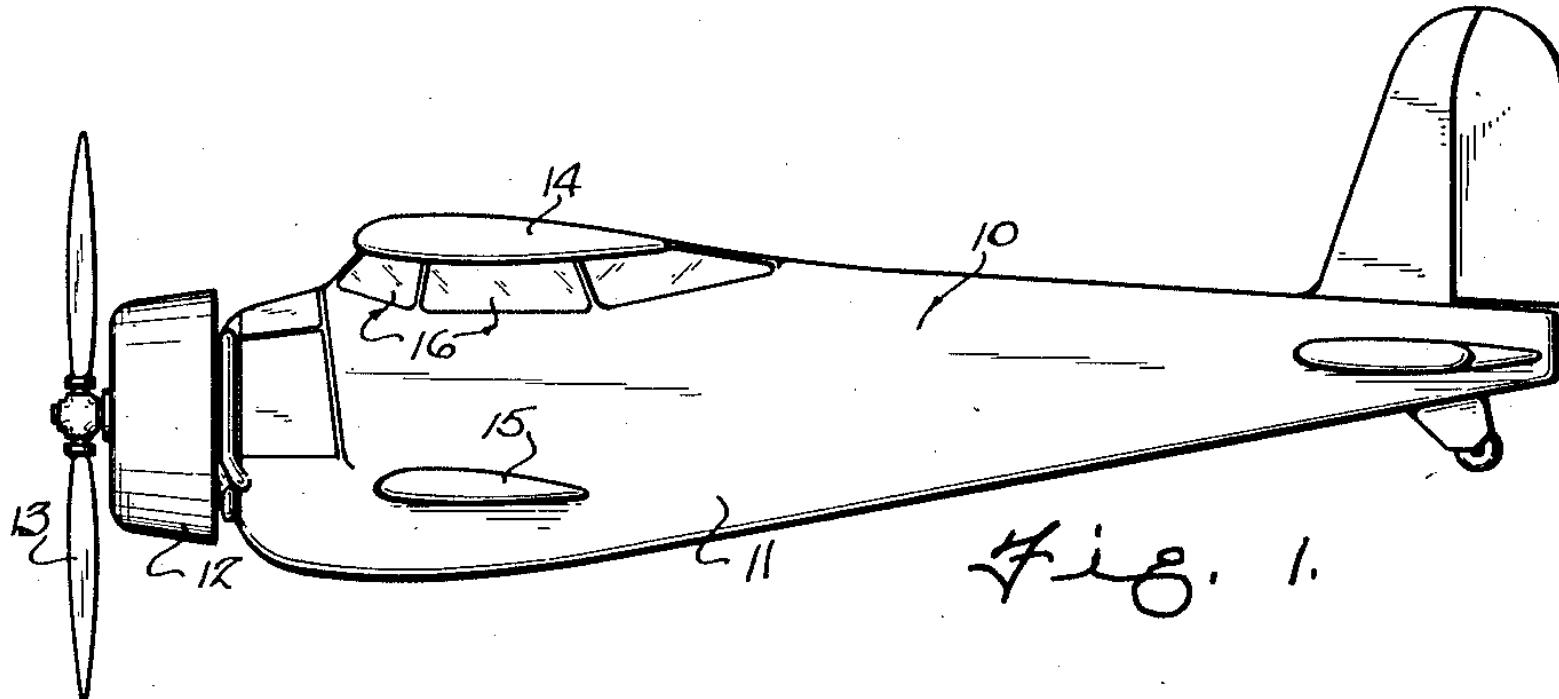
Oct. 21, 1947.

H. A. McMASTER

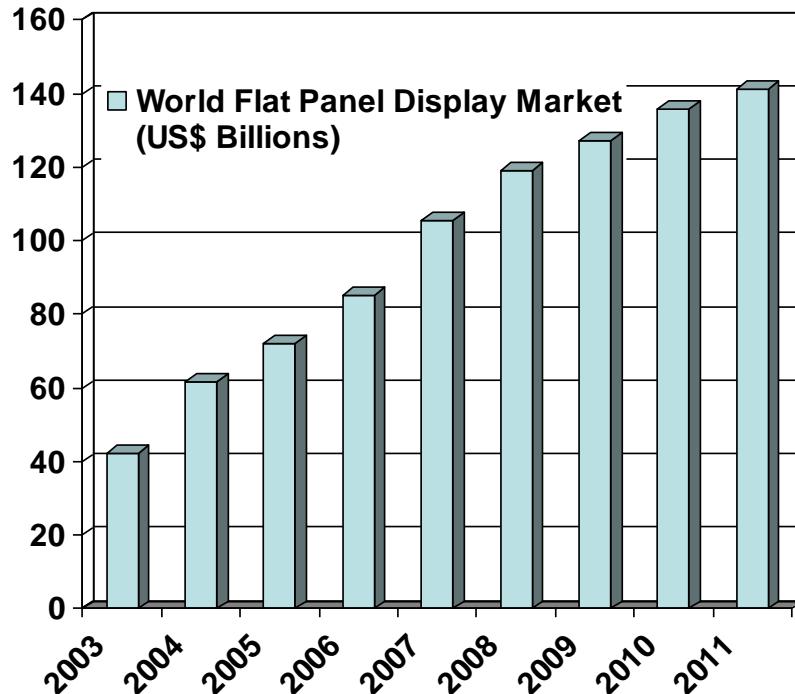
2,429,420

CONDUCTIVE COATING FOR GLASS AND METHOD OF APPLICATION

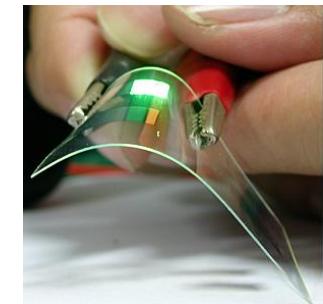
Filed Oct. 5, 1942



Motivation



German Flat Panel Display Forum



- Transparent conductive oxides (TCOs): key materials in optoelectronics

Present

Rare
Indium, etc

\$\$\$



Toxic

Cd, F, etc

Next
generation

Abundant
Indium-free

\$



Environmentally
friendly

Zn, Ti, Si

HZDR

Overview of activities

Wilde, Cornelius (FWIN),
Liedke, Vinnichenko

Bilateral, BMWi/AiF,
BMBF-TUBITAK

HZB, von Ardenne,
GfE Fremat, Bosch,
Solayer, Vaciontec,
DTF, Heliatek, CreaPhys,
Interpane, Euroglas,
LIMO, METU,
Bilkent Univ.

Transparent conductive oxides
Oxide-based nanocomposites

ZnO-based

TiO₂-based

Elevated temperature
Particle fluxes
Structure
Stoichiometry
Phase composition
Properties

Understanding upper
physical limits of performance
Achieving novel nanomaterials

SiO_x-based

Liedke, Heinig, FWIZ: Friedrich,
Schmidt

BMBF-TUBITAK
Abengoa Associated Partnership
Agreement

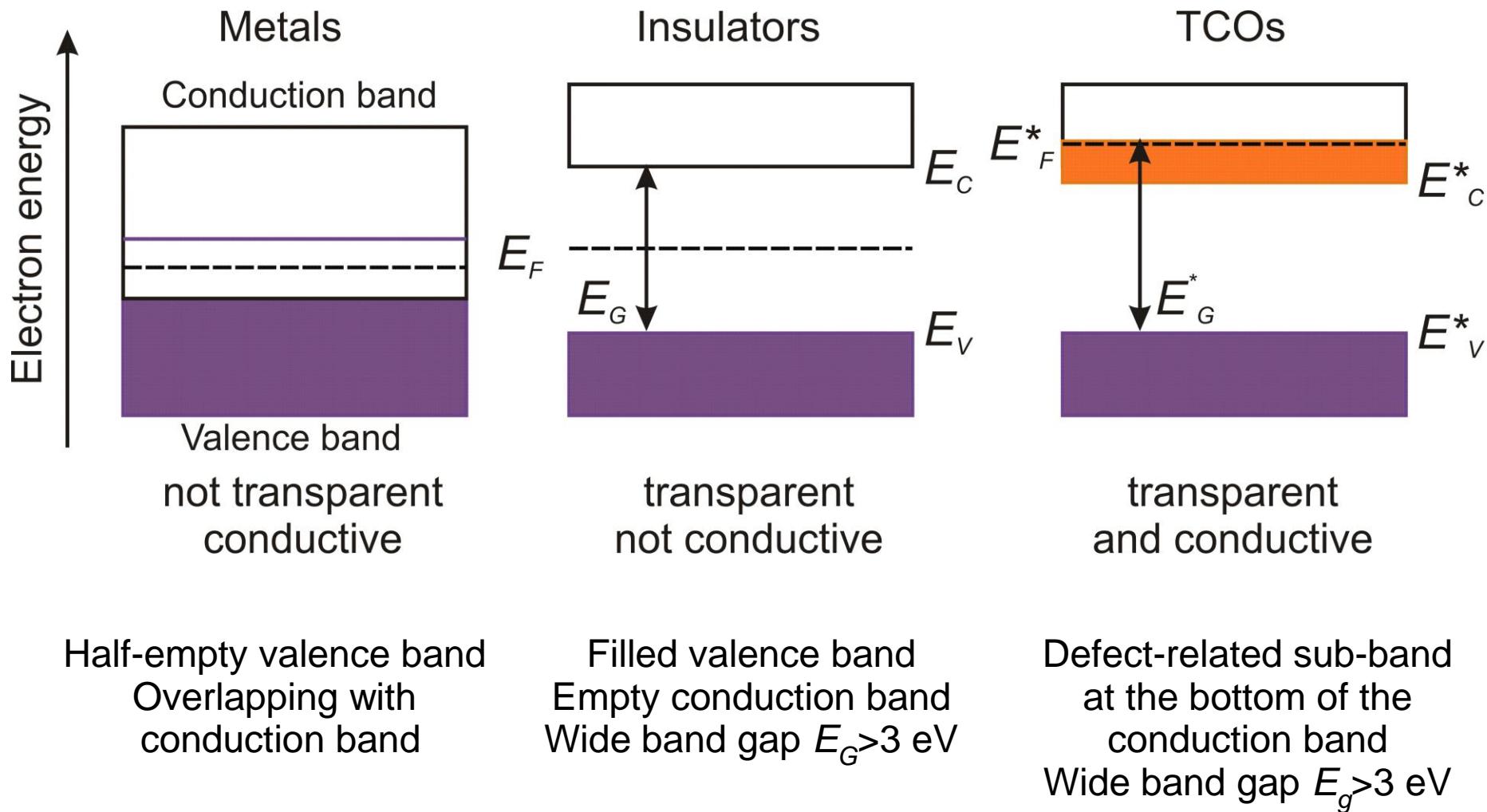
LIMO, METU, Bilkent Univ.,
Nurol, Abengoa Research

Neubert,
Cornelius (FWIN),
Vinnichenko

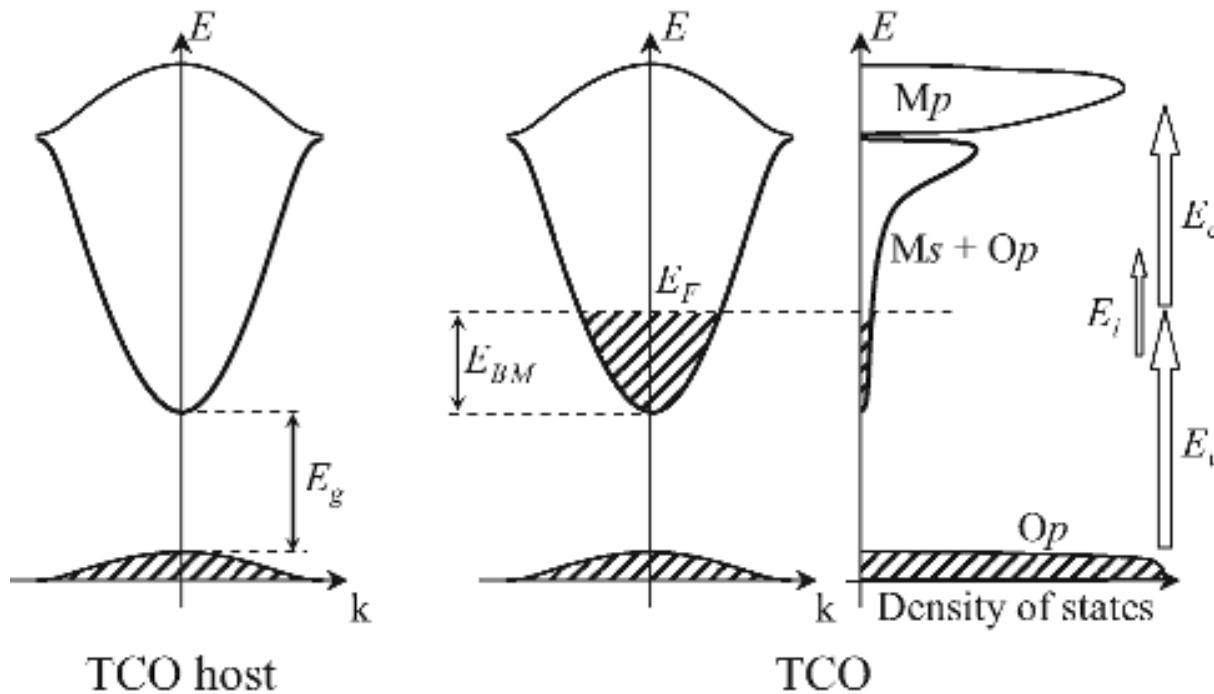
Bilateral,
BMBF MatRessource
(submitted)

FEP, DTF, Solayer,
Vaciontec, LIMO,
Euroglas,
HZDR Innovation

Basics of transparent conductive oxides (TCOs)



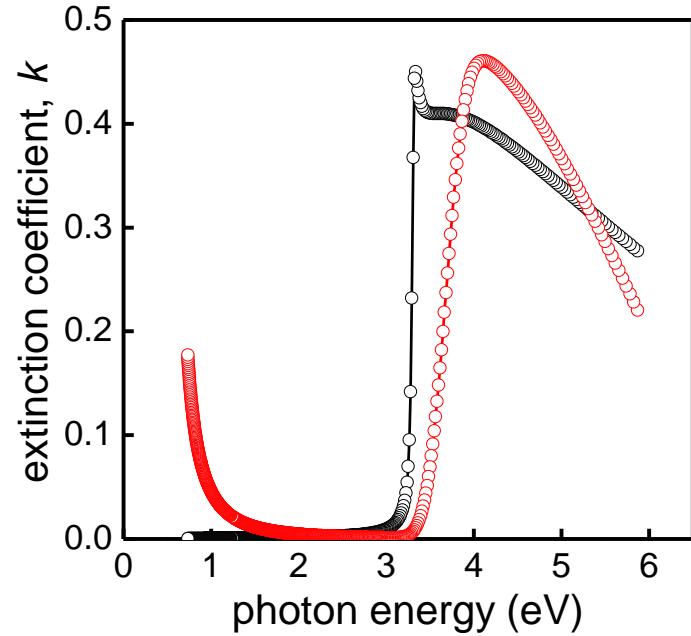
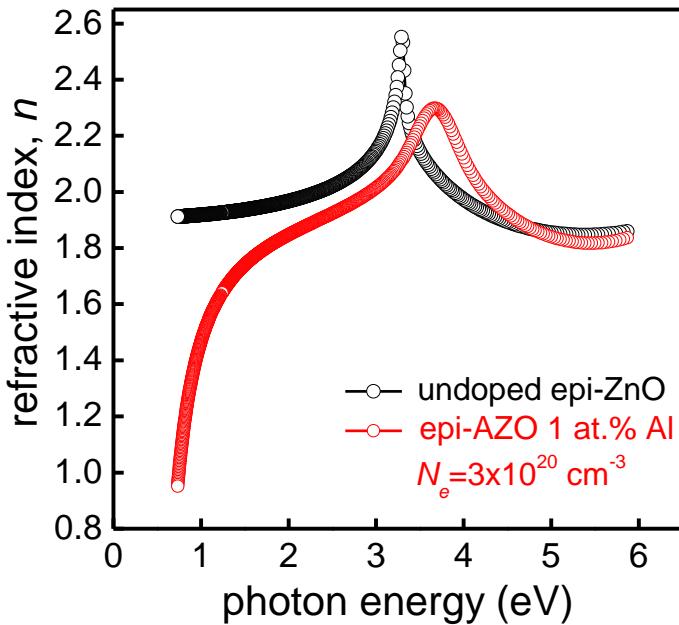
Basics of transparent conductive oxides



- Material can be highly doped: native defects + extrinsic impurities
- Degenerate n-type semiconductors

Medvedeva in Transparent Electronics: From
Synthesis to Applications, Wiley 2010

Basics of transparent conductive oxides



$$\omega_p = \sqrt{\frac{e^2 N_e}{\epsilon_0 \epsilon_\infty m^*}}$$

$$\Delta E_G \sim N_e^{2/3}$$

- Photon Energy $\leq \hbar \omega_p$: free electron absorption in the near IR
- Plasma frequency $\omega_p \leq 1$ eV
- Nearly metallic electric conductivity: $\rho \sim (1-2) \times 10^{-4} \Omega \text{ cm}$
- Photon Energy $\geq E_G$: interband transitions
- Burstein-Moss shift due to free charge carriers

$$\rho = \frac{1}{e N_e \mu_e} = \frac{m^*}{e^2 N_e \tau}$$

Sn-doped indium oxide (ITO): best understood TCO !?

What is the band gap of In_2O_3 ?

- Generally accepted: direct gap of $E_G=3.75$ eV, based on optical investigations

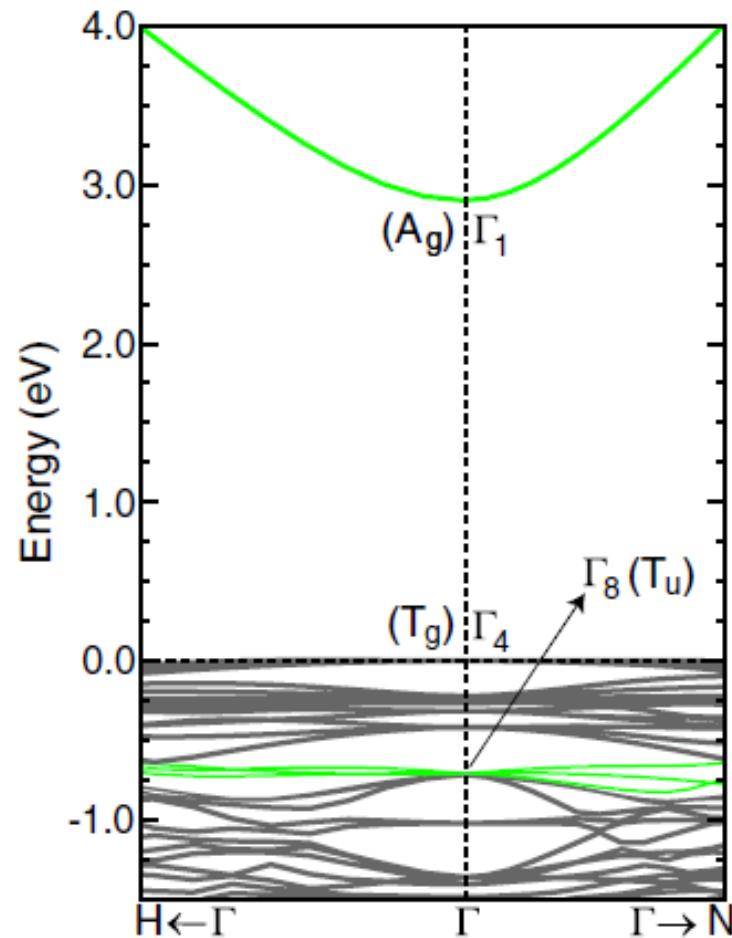
Hamberg et al, *PRB* 30, 299 (1984)

- X-ray photoelectron spectroscopy: fundamental gap is <3 eV
- In some cases optical data show absorption outset at 2.6 eV
- It is attributed to indirect transitions

Christou, et al, *JAP* 88, 5180 (2000)

McGuinness et al, *PRB* 68, 165104 (2003)

- Recent comprehensive study: fundamental band gap is not higher than 2.9 eV, direct gap
- But corresponding transitions are parity forbidden!
- Only transitions from lower levels (green) are allowed



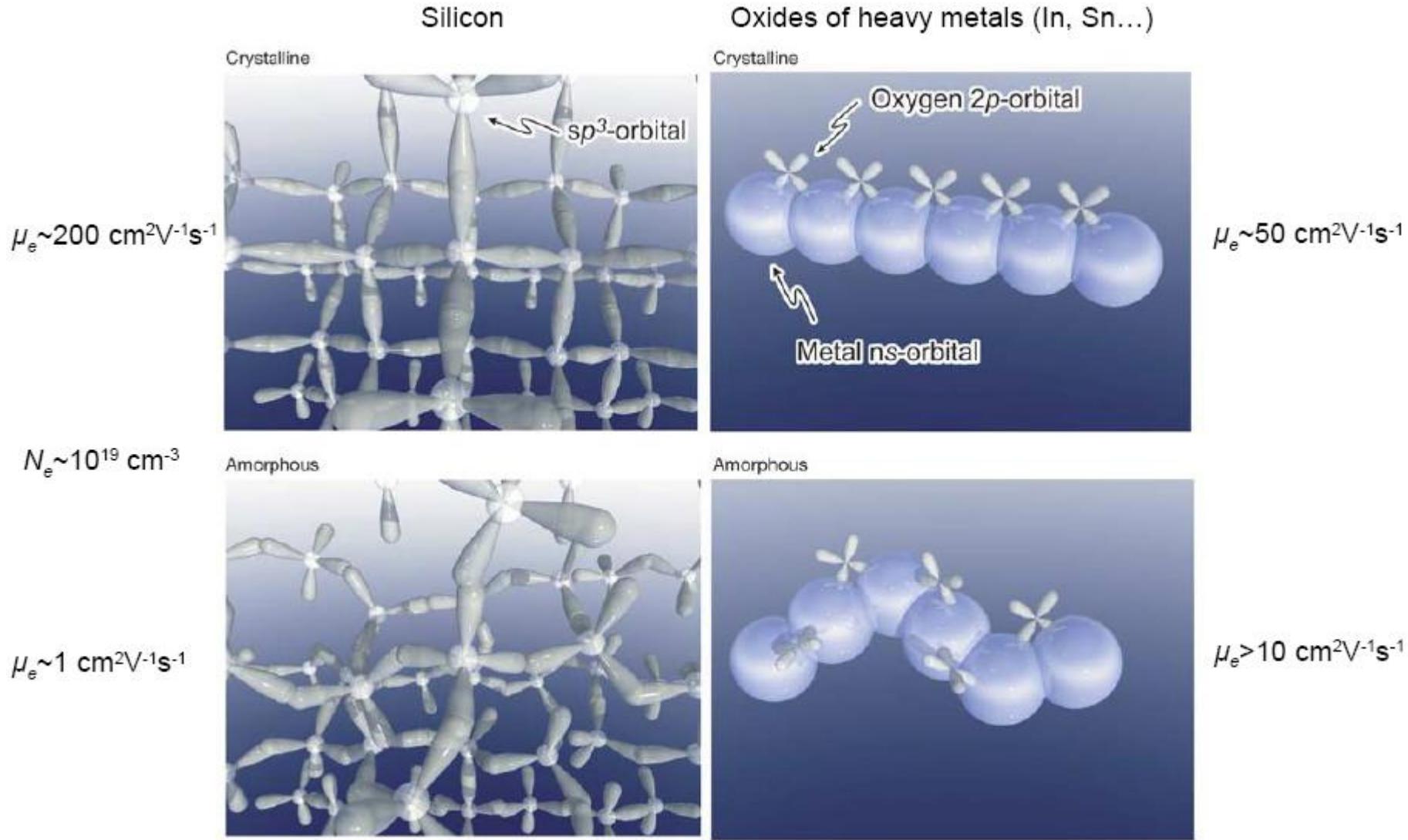
Walsh et al, *PRL* 100, 167402 (2008)

Basics of transparent conductive oxides

Exclusively post-transition metal oxides?

- CdO, In₂O₃, SnO₂, ZnO-based:
 - (n-1)d¹⁰ns² electronic configurations
 - four- (ZnO) or six-fold (CdO, In₂O₃, SnO₂) coordinated atoms
 - Conduction band bottom: metal s +oxygen p
- TiO₂-based: exception

Basics of transparent conductive oxides



Nomura et al, *Nature* 432, 488 (2004)

- Not true for TiO_2 -based TCOs!



Basics of transparent conductive oxides: TiO₂:Nb/Ta

- Difference to conventional transparent conducting oxides (TCOs):

- Conduction band bottom:

- no extended metal s-states
 - mainly formed by Ti 3d orbitals

- Different phases/polymorphs – different electrical properties:

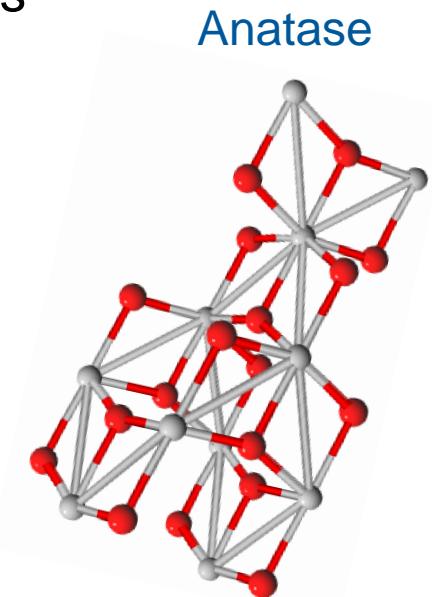
- Amorphous: non-conductive
 - Anatase: very well conductive (low m^*)
 - Rutile: only weak conductivity (high m^*)

- High refractive index

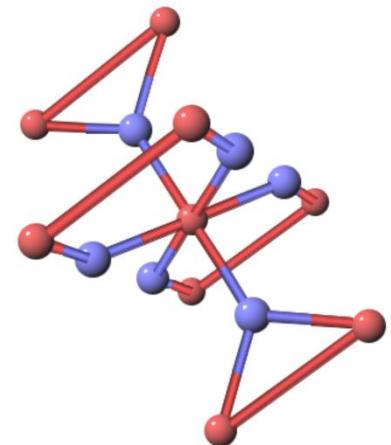
- By now highest quality films are achievable only using epitaxial substrates

- Challenges:

- introducing controllable oxygen deficiency into the material
 - control of the phase composition
 - achieving high quality polycrystalline films



Anatase



Rutile

Basics of transparent conductive oxides: $\text{TiO}_2:\text{Nb/Ta}$

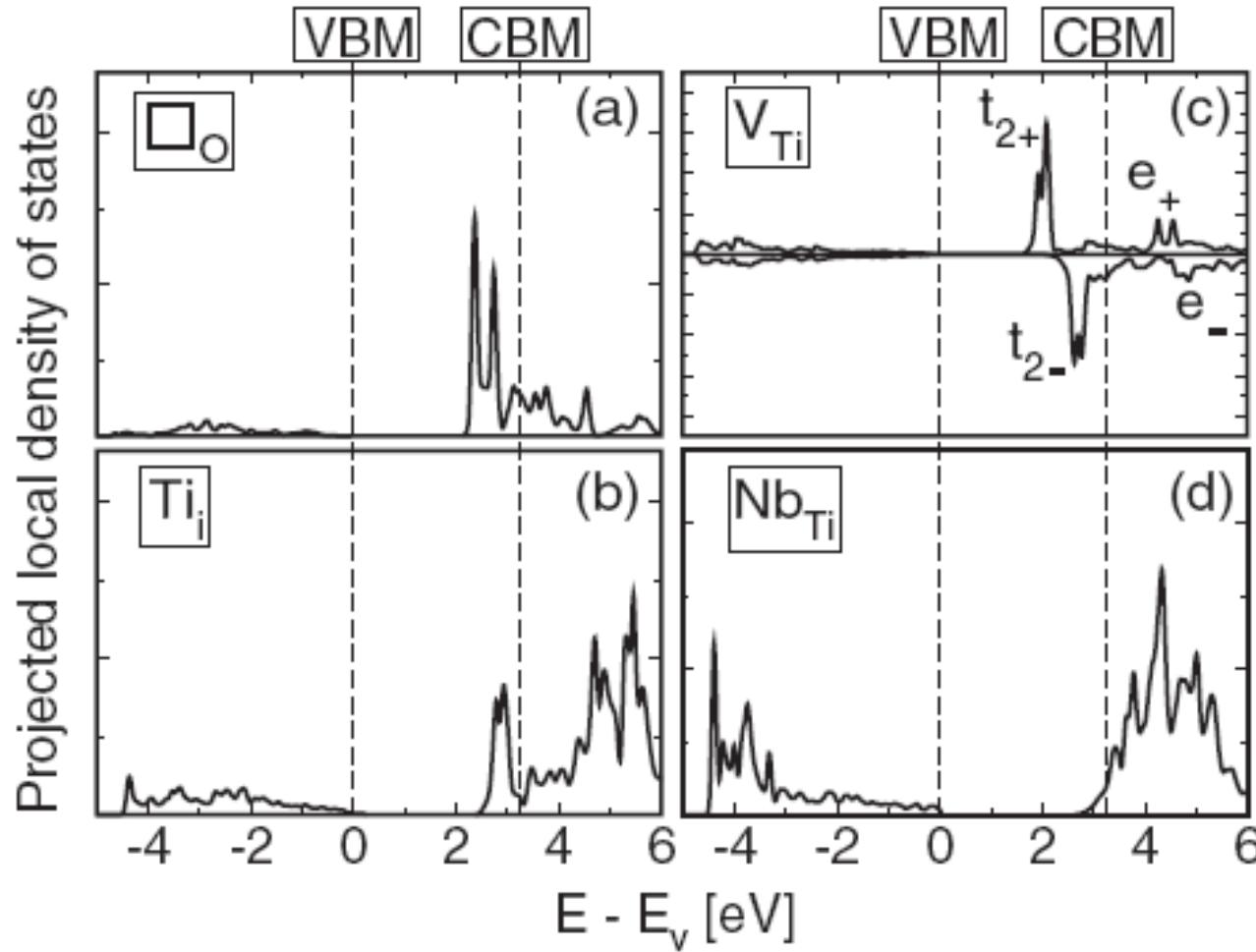
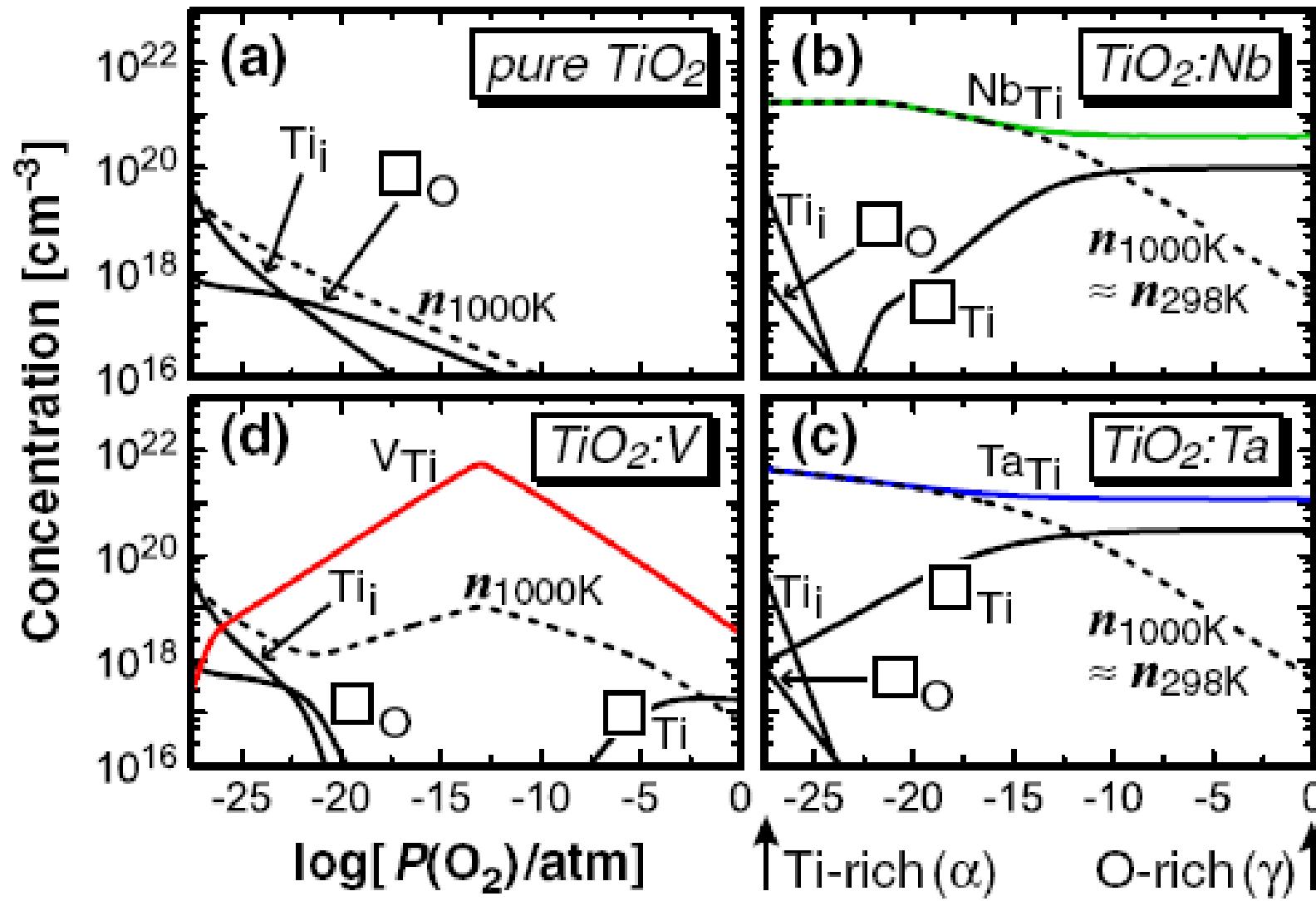


FIG. 4. Calculated local density of states (DOS) for \square_{O}^0 , Ti_i^0 , V_{Ti}^0 , and Nb_{Ti}^0 using GGA. The hosts VBM and CBM are indicated by vertical-dashed lines.

zdr

Osorio-Guillen, Lany, Zunger, Phys.Rev.Lett. 100, 036601 (2008)

Basics of transparent conductive oxides: $\text{TiO}_2:\text{Nb}/\text{Ta}$



Osorio-Guillen, Lany, Zunger, Phys.Rev.Lett. 100, 036601 (2008)

Challenges and Objectives

“... understanding of the basic physics and chemistry of metal oxide surfaces lags a decade or more behind that of metals and semiconductors...”

Henrich and Cox, The Surface Science of Metal Oxides, Cambridge University Press, 2000

- Understanding even of the properties of metal oxide films and single crystals often lags behind
- Basic understanding:
 - Defect formation
 - Incorporation and electrical activation of doping impurity
 - Formation of secondary phases and their properties
 - Limits to the charge carrier transport
- Controllability and reproducibility:
 - Fine tuning of the metal/oxygen flux
 - Understanding role of the plasma energetic species
 - Thin film microstructure and surface morphology
- Addressing these issues is crucial to ensure further progress

Experimental approach: film synthesis



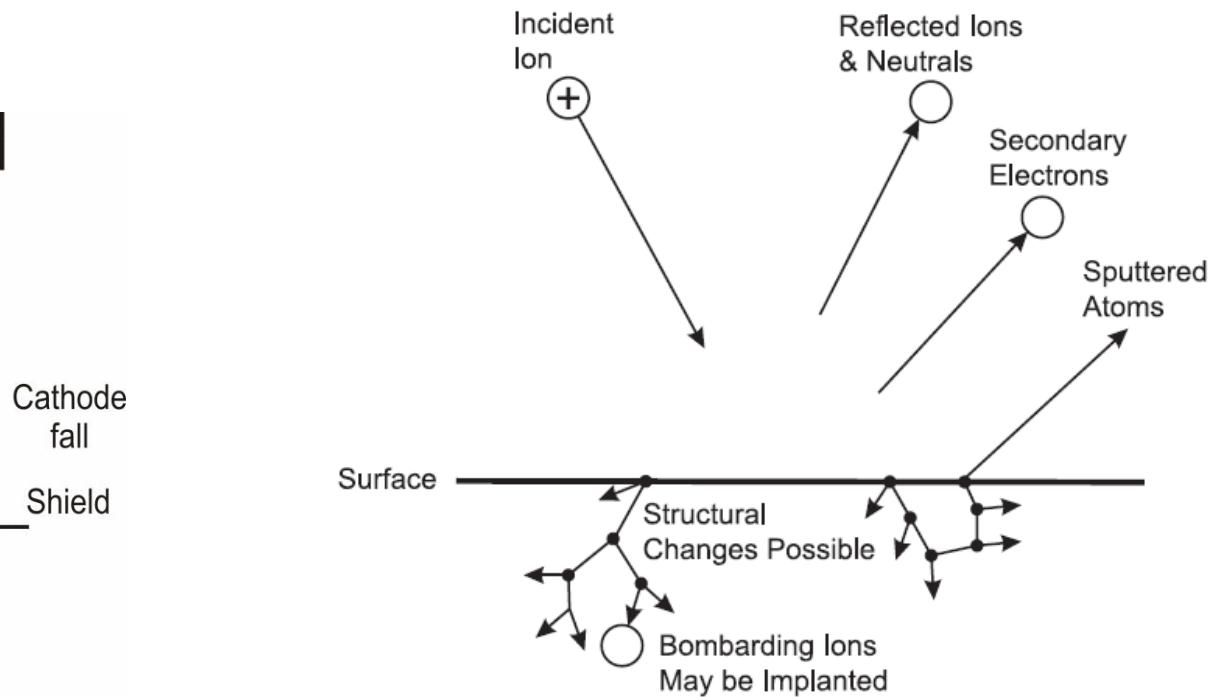
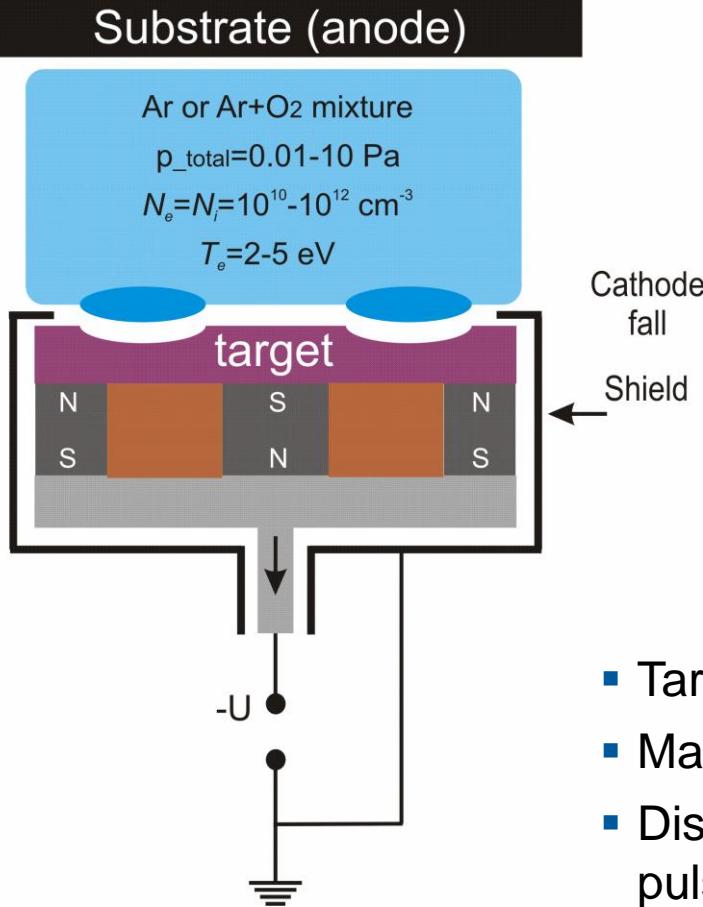
- Four sputter deposition systems
- DC and pulsed magnetron sputtering
 - Reactive (Ar + O₂), metallic (elemental and alloy) targets
 - Non-reactive (Ar), conductive (reduced) ceramic targets
- 2- and 3-inch magnetrons, balanced and unbalanced
- Energy-resolved mass spectrometry for detection of plasma ion species
- Langmuir probe with fine time resolution
- Precise tuning of metal/oxygen flux ratio:
 - Zn, Zn-Al, Zn-Ga: magnetron voltage
 - Ti, Ti-Nb: magnetron current
 - Reduced ceramic targets: optical emission of plasma intensity as a feedback

Experimental approach: film characterization



- Annealing chamber (vacuum, Ar, O₂), equipped with *in situ* four point probe for resistivity measurements
- Annealing unit is transferrable to other experimental set-up: e.g. *in situ* XANES
- *In situ* spectroscopic ellipsometers: M-2000V, M-2000FI, J.A. Woollam Inc.
- Spectral photometer: SoliSpec 3700, Shimadzu

Basics of magnetron sputtering



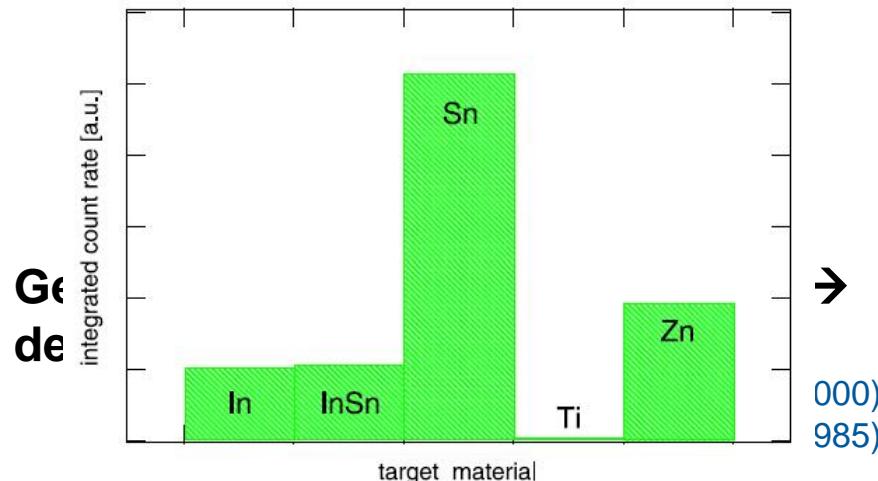
- Targets: metallic or compound
- Magnetic field configuration: balanced or unbalanced
- Discharge modes: DC, medium-frequency (MF) pulsed, RF
- Energetic particle bombardment during growth may be used as a tool to affect the film structure and properties

Ellmer, JPD 33, R17 (2000)

Role of energetic particles

ZnO:Al

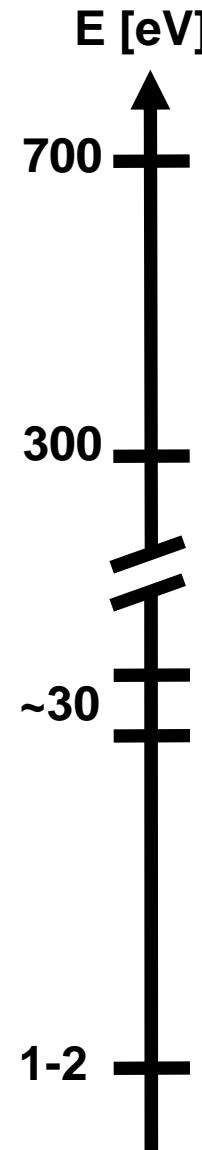
Energetic negative ions



Ellmer, Welzel, *JMR* **27** (2012)

Some ion assistance increases adatom mobility → better films

Mendelsberg et.al., *J. Phys. D* **44** (2011)
Anders, *APL* **80** (2010)



Typical highest energies in DC magnetron sputtering ($=qV_T$)

displacement energy: O

displacement energy: Zn

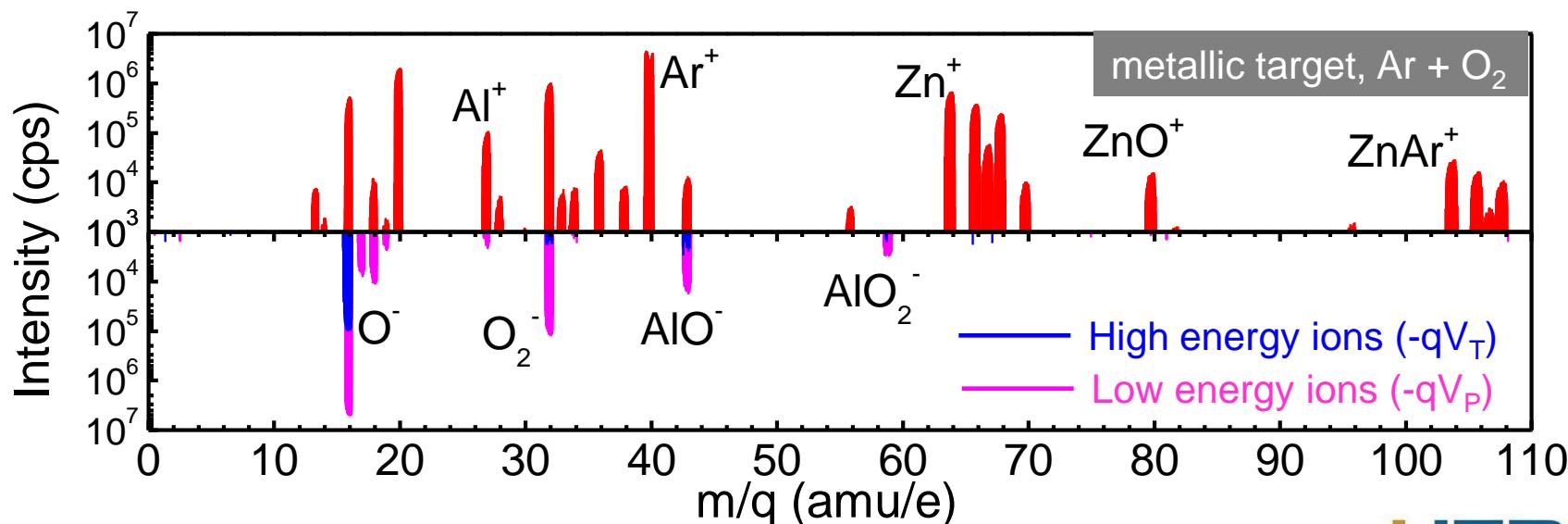
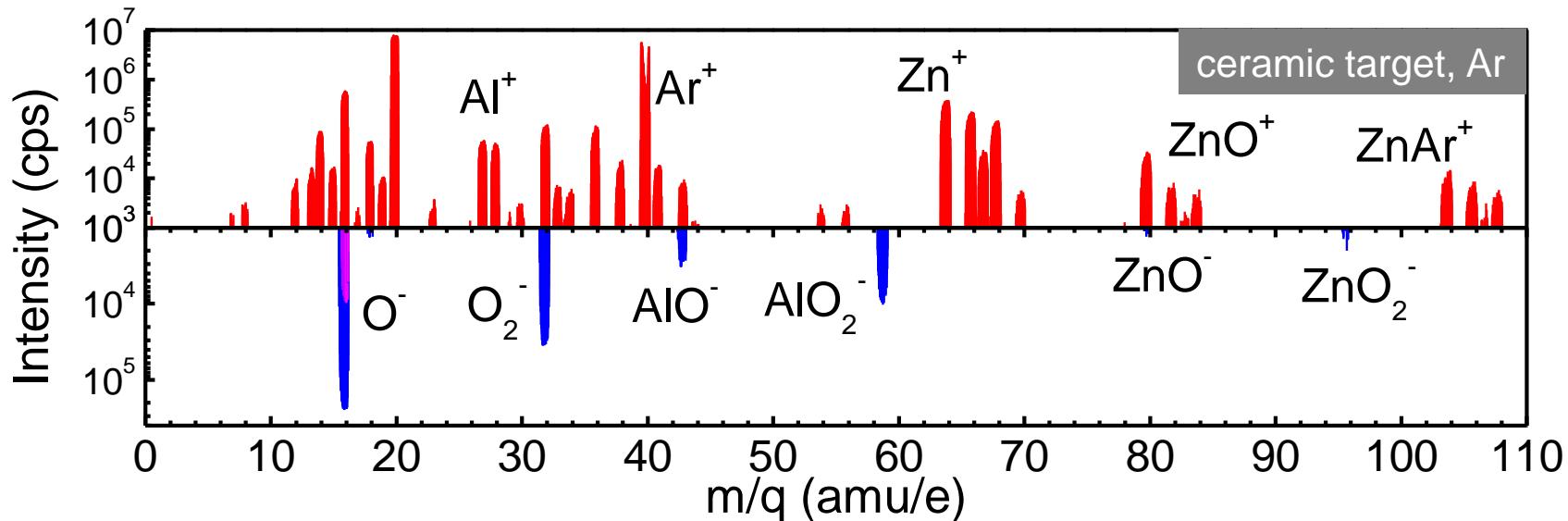
Look et.al., *APL* **75** (1999)
Redondo-Cubero, Vinnichenko, Krause et al
JAP **110** (2011)

Activation of defect annealing
S.J. Zwinkle and C. Kinoshita, *J. Nucl. Mater.* **251** (1997)

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Metallic vs ceramic targets: plasma

ZnO:Al



C. Wilde (in preparation)

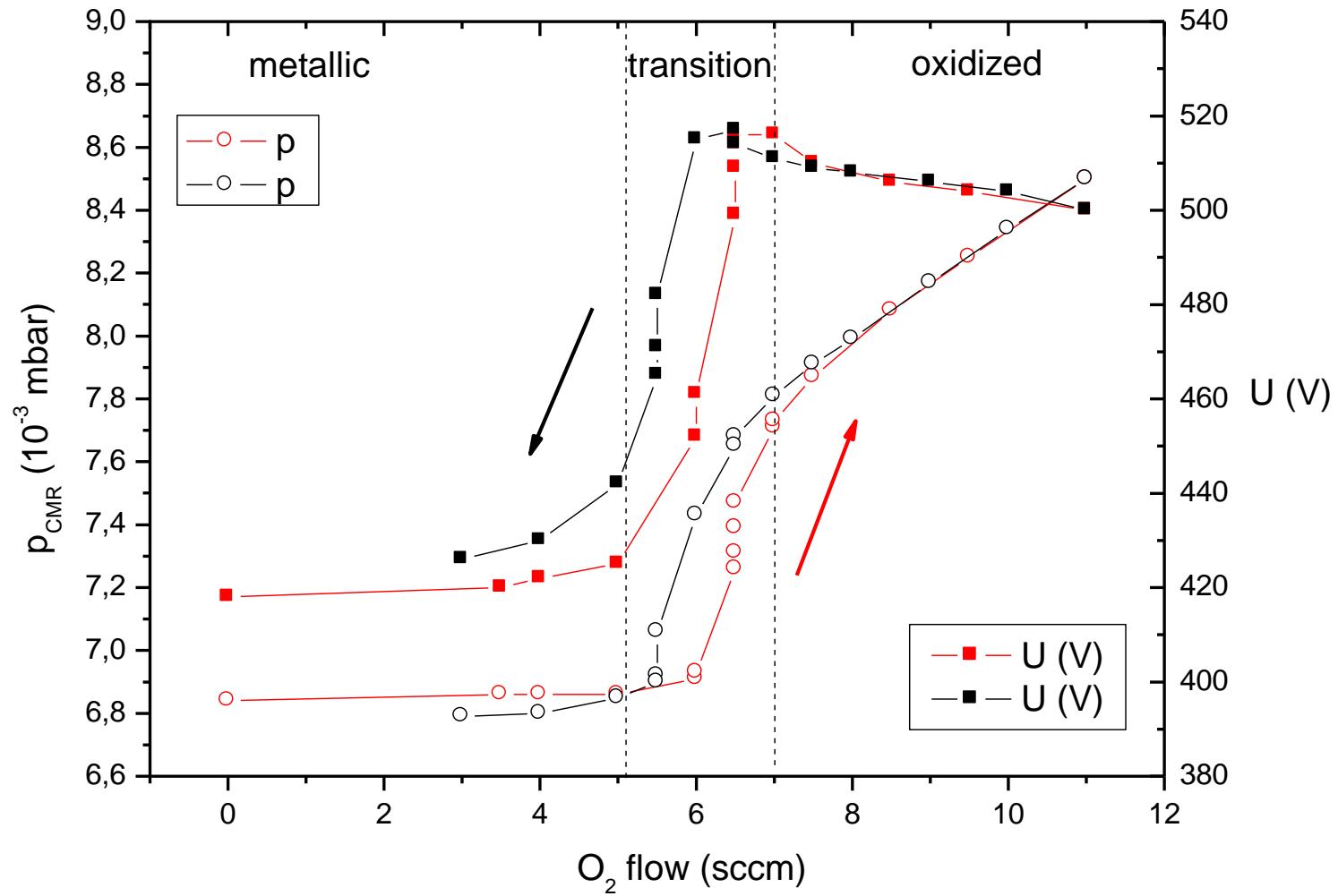
HZDR

Direct growth, reactive magnetron sputtering, variation of deposition temperature

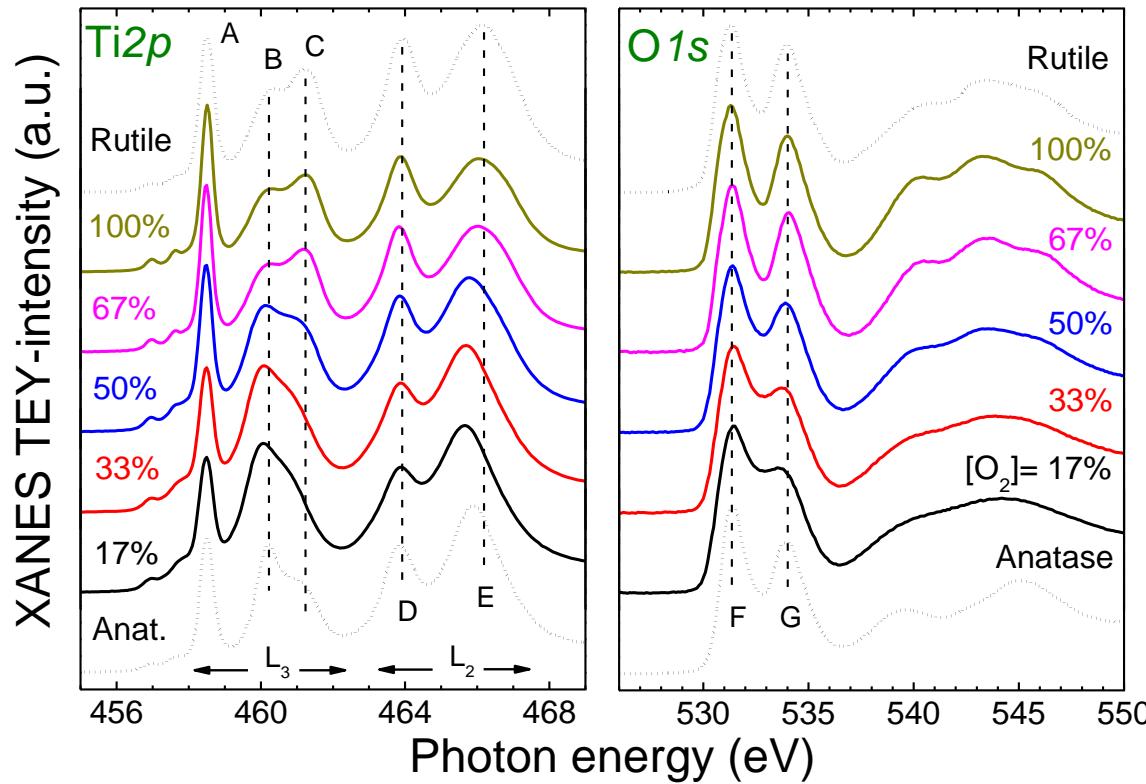
Reactive sputtering: hysteresis

TiO₂

pressure-voltage vs. flow hysteresis of Ti in (Ar,O₂) , P=500W



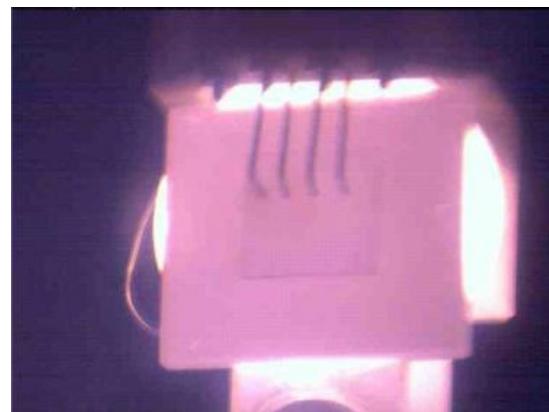
XANES data



- Ti2p spectra: 2p to 3d transitions
- $L_{3,2}$ edges: spin-orbit splitting of Ti-2p core level into $2p_{3/2}$ and $2p_{1/2}$
- XANES shows differences between as-grown disordered anatase- and rutile-like films, which are indistinguishable by XRD

Gago, Vinnichenko et al. *Plasma Process. Polym.* 7, 813 (2010)

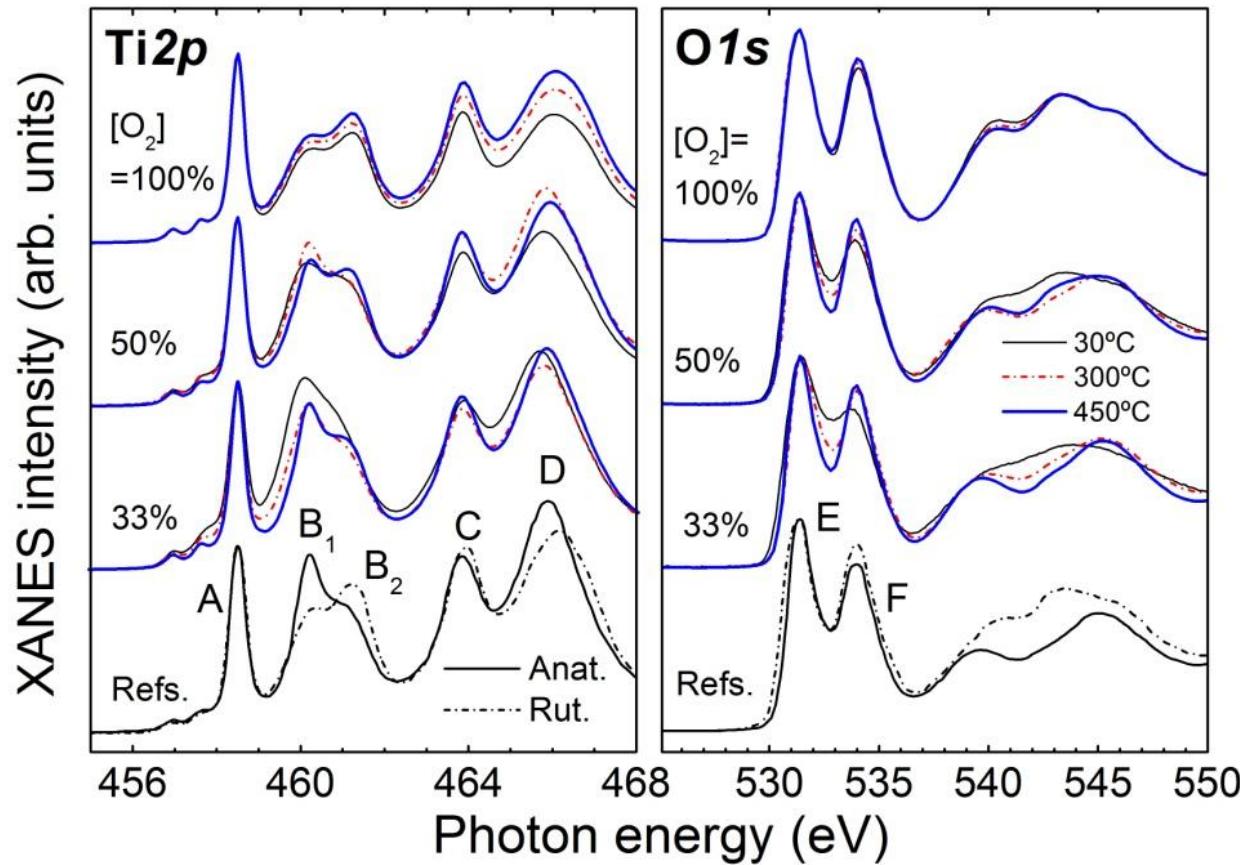
Two-step process, DC magnetron sputtering of reduced ceramic targets



deposition of amorphous film
(no heating)
reduced ceramic target

vacuum annealing at ~400°C, 1 hour

XANES data

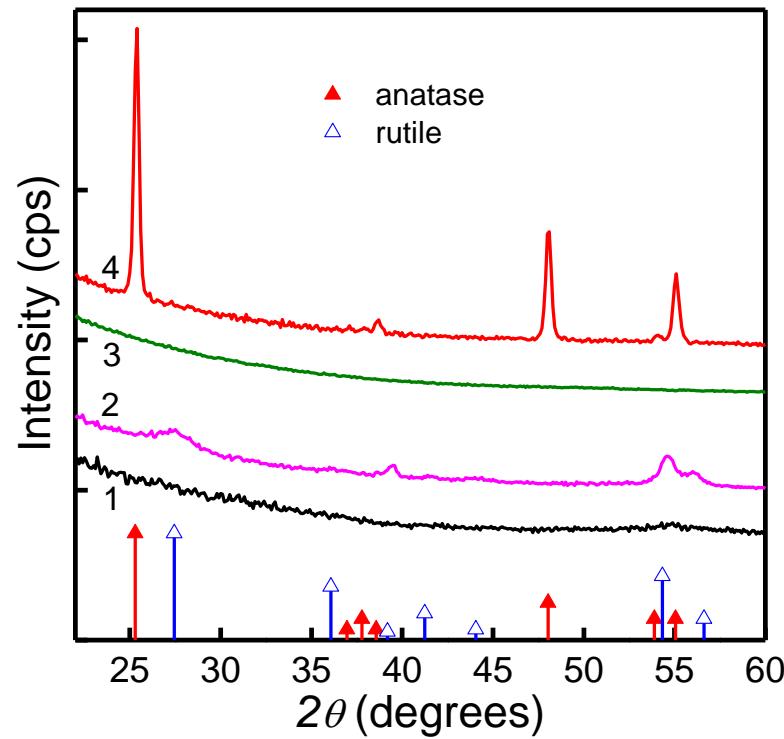
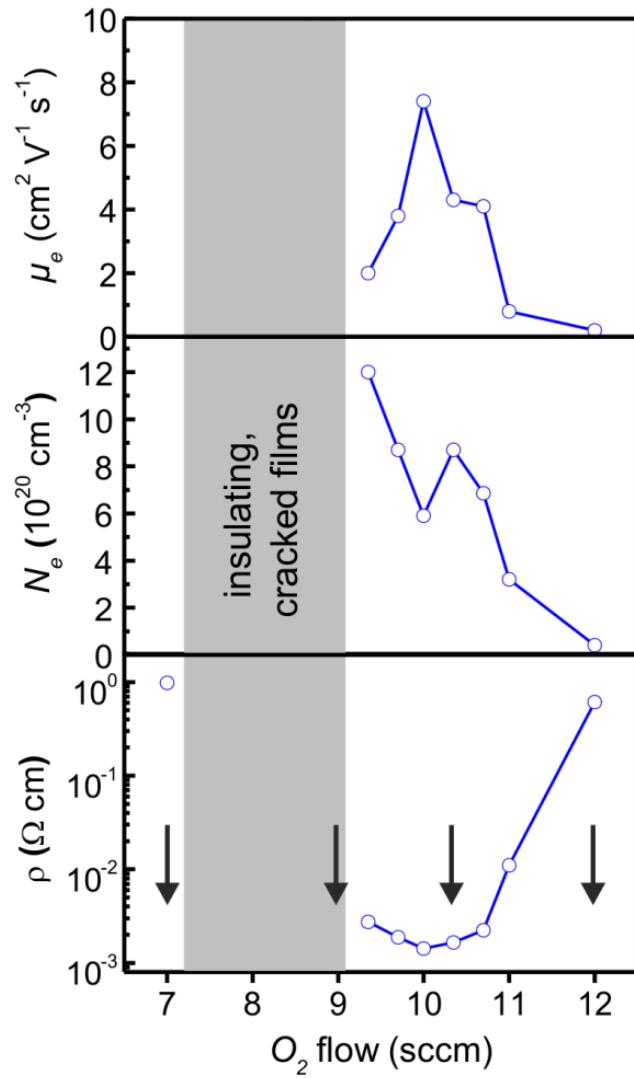


- Amorphous anatase-like films readily crystallize in good polycrystalline anatase TiO₂
- Disordered nc-rutile TiO₂ films remain stable upon annealing

Gago, Redondo-Cubero, Vinnichenko, Vazquez, *Chem.Phys.Lett.* 511, 367 (2011)

Relation to the structure and properties

TiO₂:Nb

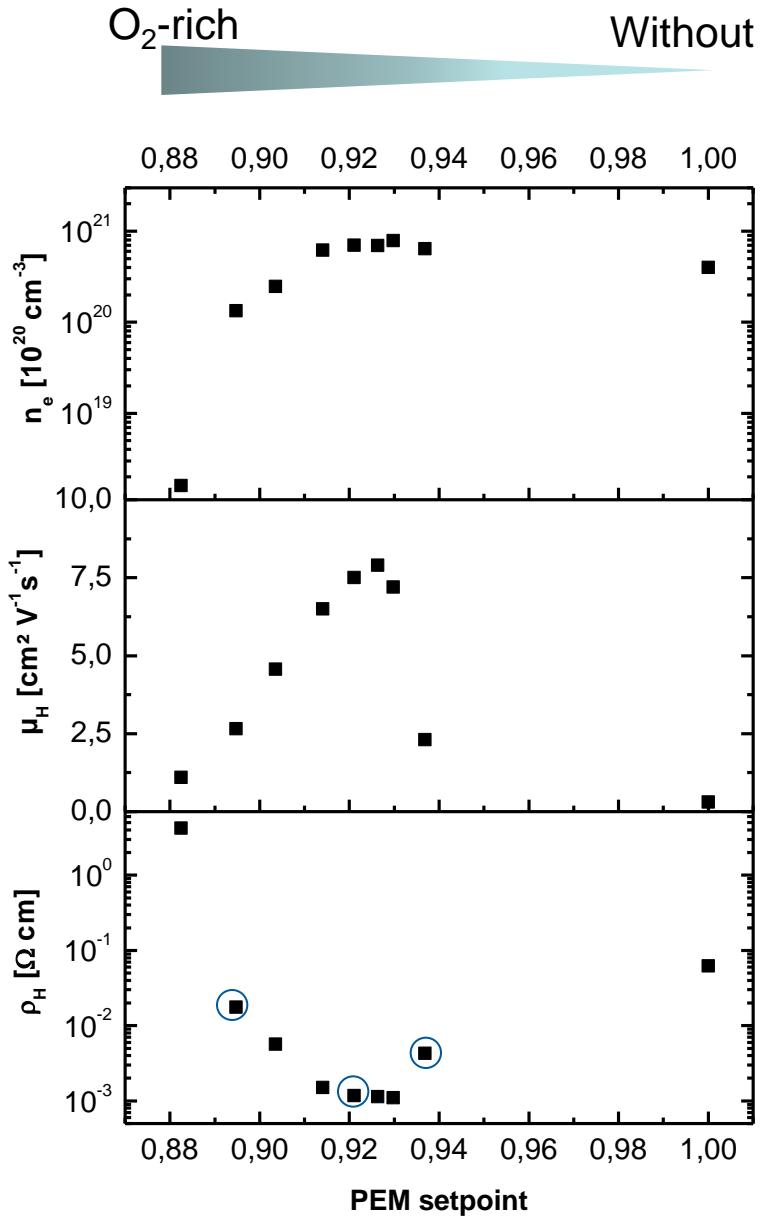


- 1: as deposited (O₂ flow 9 sccm)
- 2: the same films after annealing in vacuum
- 3: as deposited (O₂ flow 10.35 sccm):
- 2: the same films after annealing in vacuum

Vinnichenko et al (in preparation)

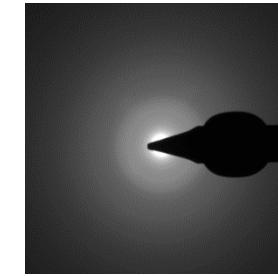
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TiO₂:Ta: structure and properties

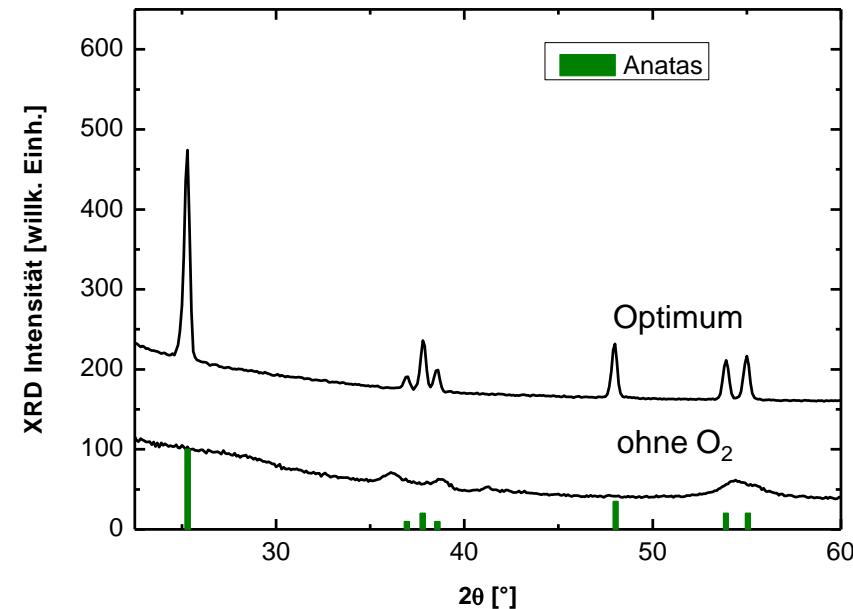


As-deposited

- insulating
- XRD-amorph.
- TEM-amorph.



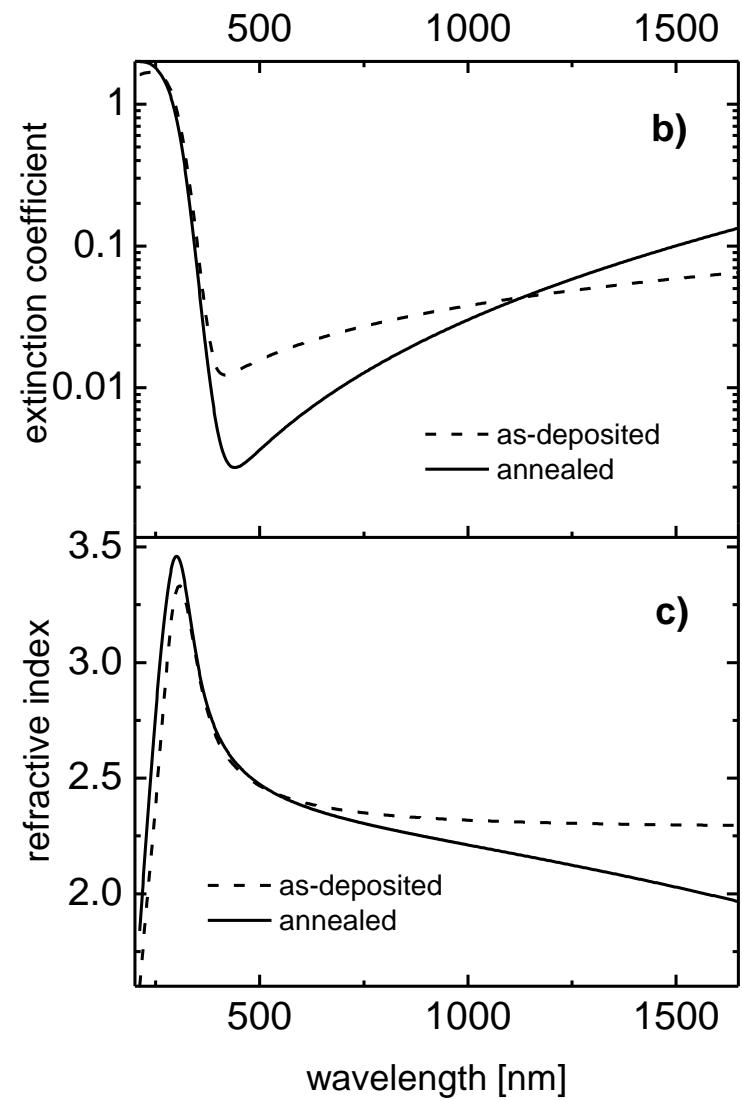
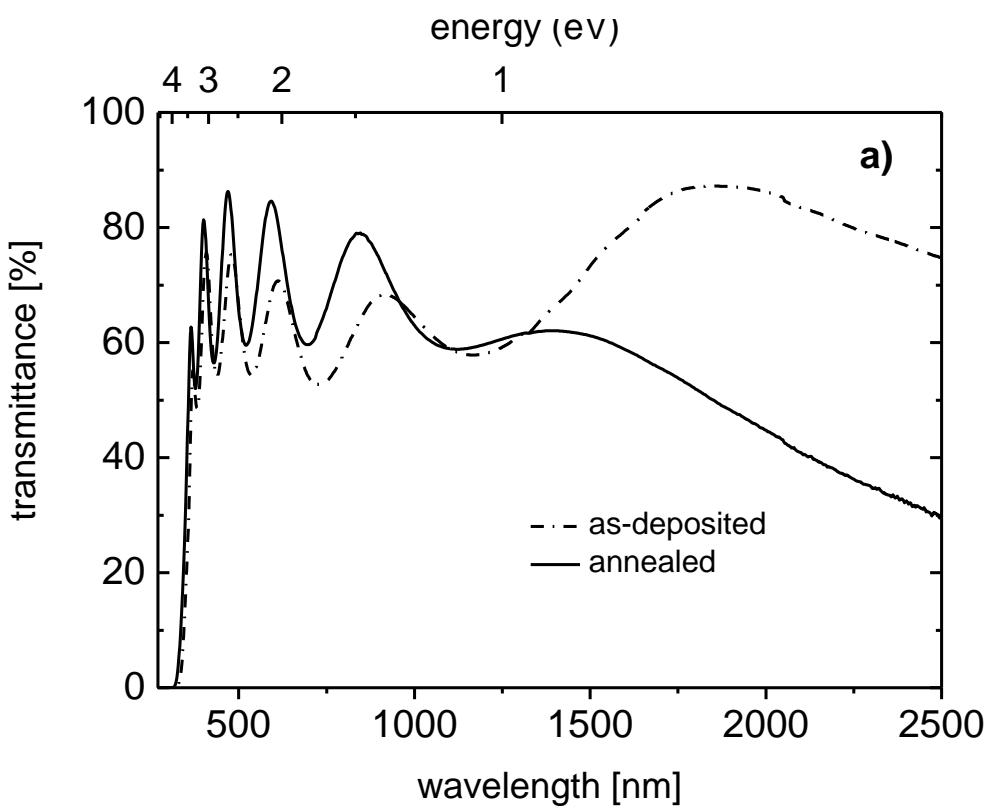
Annealed



Neubert et al (in preparation)

HZDR

TiO₂:Ta: optical properties, optimized films



Neubert et al (in preparation)

HZDR

Summary

- The polycrystalline anatase TiO_2 -based films with properties above current state of the art are realized by magnetron sputtering
- High-precision control of the oxygen deficiency and prevention of the rutile seed layer formation are crucial

Acknowledgements

- J. Fiedler (FWIM), A. Kolitsch (FWIZ), A. Mücklich (FWIZ)
- M. Jünghähnel (FEP, Dresden), R. Gago (CSIC-ICMM, Madrid)
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